

High-mobility two-dimensional electron gas with quantized states in polar-discontinuity doped $\text{LaInO}_3/\text{BaSnO}_3$ heterostructure grown by molecular beam epitaxy

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Transistor applications of semiconducting oxides require, both high room-temperature electron mobilities (μ_{RT}) and high charge carrier densities (CCDs), ideally realized with a two-dimensional electron gas (2DEG). So far, prototype oxide 2DEG systems have either high μ_{RT} but limited CCD such as modulation-doped $(\text{Al}_x\text{Ga}_{1-x})_2\text{O}_3/\text{Ga}_2\text{O}_3$, or a high CCD but low μ_{RT} such as the polar-discontinuity doped $\text{LaAlO}_3/\text{SrTiO}_3$ interface. Interfacing the more suitable, wide-bandgap, nonpolar semiconductor BaSnO_3 (BSO), having high bulk μ_{RT} (up to $320 \text{ cm}^2/\text{Vs}$), with polar LaInO_3 (LIO) is predicted to create and confine a 2DEG with CCD up to $2 \times 10^{14} \text{ cm}^{-2}$ for the SnO_2/LaO interface termination.

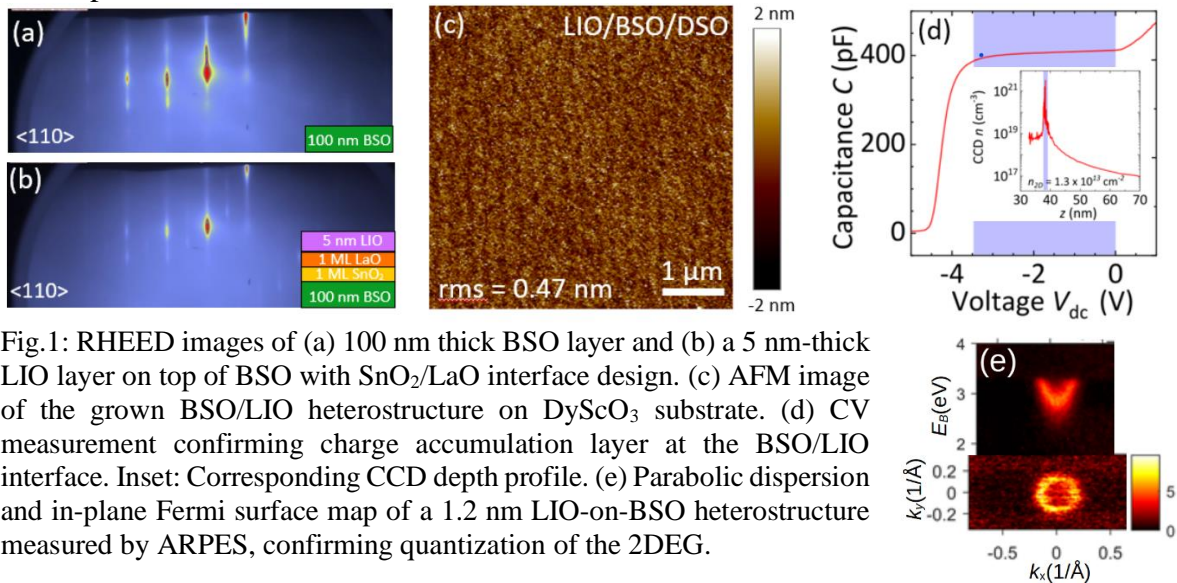


Fig.1: RHEED images of (a) 100 nm thick BSO layer and (b) a 5 nm-thick LIO layer on top of BSO with SnO_2/LaO interface design. (c) AFM image of the grown BSO/LIO heterostructure on DyScO_3 substrate. (d) CV measurement confirming charge accumulation layer at the BSO/LIO interface. Inset: Corresponding CCD depth profile. (e) Parabolic dispersion and in-plane Fermi surface map of a 1.2 nm LIO-on-BSO heterostructure measured by ARPES, confirming quantization of the 2DEG.

We demonstrate the adsorption-controlled growth of the LIO[1] on BSO heterostructure by molecular beam epitaxy using a shutter sequence to control the SnO_2/LaO interface termination. The films were analyzed by reflection high-energy electron diffraction (RHEED) [Figs. 1(a) and 1(b)], x-ray diffraction, atomic force microscopy (AFM) [Fig. 1(c)]. The interface structure is investigated by cross-sectional transmission-electron microscopy. The formation of the quantized 2DEG at their interface is confirmed by capacitance-voltage (CV) [Fig. 1(d)] and angular-resolved photo-electron spectroscopy (ARPES) [Fig. 1(e)]. Van der Pauw-Hall measurements confirm $\text{CCD} > 10^{13} \text{ cm}^{-2}$ and $\mu_{\text{RT}} > 100 \text{ cm}^2/\text{Vs}$.

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